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Charge Noise in Semiconductor Spin Qubits 9 & 10 June 2022 Rüschlikon, Switzerland



Quantum Silicon Grenoble

























Outlines











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W.H. Matteus et al, PRL 1986 D.L. Gilden et al, Science 1995 B.J. West and M.F. Shlesinger, IJMPB 1989















What are the sources of **charge noise**? \mathbf{P}_{b1} 0 P_{b0} Si 0 Interstitial defects (in gate Si Si Si S Si S oxide or bulk) Dangling bonds at interfaces



cnrs

















Effects of Interfaces

Si/SiO₂ - decreased charge noise at back interface (BOX)

Spacers and doped reservoirs detrimental source of CN

Detected charge noise between 0.1 and 100 µeV²/Hz @1Hz





















Outlines























CNrs

FDSOI nMOS device







 $E_{\rm VS}$ ranging from 80 to 300 $\mu {\rm eV}$









 $E_{\rm VS}$ fluctuations of 4 $\mu {\rm eV}/{\sqrt{\rm Hz}}$ @1Hz













Coherence time extended from $T_2^* \approx 330$ ns to $T_2^{\text{CPMG64}} \approx 300 \ \mu\text{s}$















Outlook











Deeper characterisation of fluctuator species

$$f_i = f_0 e^{-\frac{E_\alpha}{k_B T}}$$
$$E_\alpha = k_B T \ln\left(\frac{f_i}{f_0}\right)$$

In-situ doped reservoir devices - no implantation

Accumulation gate reservoirs - no annealing

Mass characterization at < 2 K using cryo-prober (many-electron and fewelectron regimes) on 300 mm wafers

Move towards purified Si-28 wafers has promising implications for electron coherence



Bluefors cryo-prober

Spin qubits in semiconductors



CINITS

Probing charge noise using displacement-induced spin orbit coupling LP1LH1 RH2 RH3 [110] B, [110] 1 µm LH3 LH2 RH1 RP1 50 Pcal 40 0.25 0.89 ∆t (ns) 05 20 10 0 -60 -40 -20 20 40 60 0 B_ (mT)

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Jadot Nat. Nanotechnol. 16, 570 (2021)





